

SECTION G — PHYSICS

G01 MEASURING; TESTING

G01Q SCANNING-PROBE TECHNIQUES OR APPARATUS; APPLICATIONS OF SCANNING-PROBE TECHNIQUES, e.g. SCANNING-PROBE MICROSCOPY [SPM] [2010.01]

Note(s) [2010.01]

In this subclass, the first place priority rule is applied, i.e. at each hierarchical level, in the absence of an indication to the contrary, classification is made in the first appropriate place.

10/00	Scanning or positioning arrangements, i.e. arrangements for actively controlling the movement or position of the probe [2010.01]	60/06	• • SNOM [Scanning Near-field Optical Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]
10/02	• Coarse scanning or positioning [2010.01]	60/08	• • MFM [Magnetic Force Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]
10/04	• Fine scanning or positioning [2010.01]	60/10	• STM [Scanning Tunnelling Microscopy] or apparatus therefor, e.g. STM probes [2010.01]
10/06	• • Circuits or algorithms therefor [2010.01]	60/12	• • STS [Scanning Tunnelling Spectroscopy] [2010.01]
20/00	Monitoring the movement or position of the probe [2010.01]	60/14	• • STP [Scanning Tunnelling Potentiometry] [2010.01]
20/02	• by optical means [2010.01]	60/16	• • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]
20/04	• Self-detecting probes, i.e. wherein the probe itself generates a signal representative of its position, e.g. piezo-electric gauge [2010.01]	60/18	• SNOM [Scanning Near-Field Optical Microscopy] or apparatus therefor, e.g. SNOM probes [2010.01]
30/00	Auxiliary means serving to assist or improve the scanning probe techniques or apparatus, e.g. display or data processing devices [2010.01]	60/20	• • Fluorescence [2010.01]
30/02	• Non-SPM analysing devices, e.g. SEM [Scanning Electron Microscope], spectrometer or optical microscope [2010.01]	60/22	• • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]
30/04	• Display or data processing devices [2010.01]	60/24	• AFM [Atomic Force Microscopy] or apparatus therefor, e.g. AFM probes [2010.01]
30/06	• • for error compensation [2010.01]	60/26	• • Friction force microscopy [2010.01]
30/08	• Means for establishing or regulating a desired environmental condition within a sample chamber [2010.01]	60/28	• • Adhesion force microscopy [2010.01]
30/10	• • Thermal environment [2010.01]	60/30	• • Scanning potential microscopy [2010.01]
30/12	• • Fluid environment [2010.01]	60/32	• • AC mode [2010.01]
30/14	• • • Liquid environment [2010.01]	60/34	• • • Tapping mode [2010.01]
30/16	• • Vacuum environment [2010.01]	60/36	• • DC mode [2010.01]
30/18	• Means for protecting or isolating the interior of a sample chamber from external environmental conditions or influences, e.g. vibrations or electromagnetic fields [2010.01]	60/38	• • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]
30/20	• Sample handling devices or methods [2010.01]	60/40	• • • Conductive probes [2010.01]
40/00	Calibration, e.g. of probes [2010.01]	60/42	• • • Functionalisation [2010.01]
40/02	• Calibration standards or methods of fabrication thereof [2010.01]	60/44	• SICM [Scanning Ion-Conductance Microscopy] or apparatus therefor, e.g. SICM probes [2010.01]
60/00	Particular types of SPM [Scanning-Probe Microscopy] or apparatus therefor; Essential components thereof [2010.01]	60/46	• SCM [Scanning Capacitance Microscopy] or apparatus therefor, e.g. SCM probes [2010.01]
60/02	• Multiple-type SPM, i.e. involving two or more SPM techniques [2010.01]	60/48	• • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]
60/04	• • STM [Scanning Tunnelling Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]	60/50	• MFM [Magnetic Force Microscopy] or apparatus therefor, e.g. MFM probes [2010.01]
		60/52	• • Resonance [2010.01]
		60/54	• • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]
		60/56	• • • Probes with magnetic coating [2010.01]
		60/58	• SThM [Scanning Thermal Microscopy] or apparatus therefor, e.g. SThM probes [2010.01]
		60/60	• SECM [Scanning Electro-Chemical Microscopy] or apparatus therefor, e.g. SECM probes [2010.01]

G01Q

70/00 General aspects of SPM probes, their manufacture or their related instrumentation, insofar as they are not specially adapted to a single SPM technique covered by group G01Q 60/00 [2010.01]

70/02 • Probe holders [2010.01]

70/04 • • with compensation for temperature or vibration induced errors [2010.01]

70/06 • Probe tip arrays [2010.01]

70/08 • Probe characteristics [2010.01]

70/10 • • Shape or taper [2010.01]

70/12 • • • Nano-tube tips [2010.01]

70/14 • • Particular materials [2010.01]

70/16 • Probe manufacture [2010.01]

70/18 • • Functionalisation [2010.01]

80/00 Applications, other than SPM, of scanning-probe techniques (manufacture or treatment of micro-structures B81C; manufacture or treatment of nano-structures B82B 3/00; recording or reproducing information using near-field interaction G11B 9/12, G11B 11/24 or G11B 13/08) [2010.01]

90/00 Scanning-probe techniques or apparatus not otherwise provided for [2010.01]